# Kurukshetra University, Kurukshetra

(Established by the State Legislature Act-XII of 1956) ("A++" Grade, NAAC Accredited)



Syllabus of the Programme for Post Graduate Programme

M.Sc Electronic Science I & II sem.

as per NEP 2020 Curriculum and Credit Framework for Postgraduate Programme

With Multiple Entry-Exit, Internship and CBCS-LOCF With effect from the session 2024-25 (in phased manner)

DEPARTMENT OF ELECTRONIC SCIENCE FACULTY OF SCIENCE

KURUKSHETRA UNIVERSITY, KURUKSHETRA -136119 HARYANA, INDIA

Chairman, Electronic Science Deptt. Kurukshetra University, KURUKSHETRA-136119.

	w.e.f. Session: 2024-25		
	Part A - Introduction		
Name of Programme	M.Sc. Electronic Science		
Semester	First		
Name of the Course	Semiconductor Devices for In	tegrated Circuits	
Course Code	M24-ELE-101		
Course Type	CC1	-	
Level of the course	400-499		
Pre-requisite for the course Course Learning Outcomes (CLC	NIL		1
a tho	CLO101.2: Reproduce the el	ectifical characteristics of	
After completing this course, the learner will be able to:	CLO101.3: Explain the behave systems with the h	them in various semiconductions vior of Metal oxide semicon telp of energy band diagrams. The devices with desired specific processing the semiconduction of the semiconduction	nductor (MOS
learner will be able to:	CLO101.3: Explain the behave systems with the heave systems with the heave close to the close of	them in various semiconductions vior of Metal oxide semicon nelp of energy band diagrams.  T devices with desired spenapplications.	nductor (MOS)
After completing this course, the learner will be able to:  Credits	switching and amp CLO101.3: Explain the behave systems with the head CLO101.4: Develop MOSFE electronic circuit a Theory	them in various semiconductions vior of Metal oxide semicon telp of energy band diagrams. The devices with desired specific processing the semiconduction of the semiconduction	nductor (MOS) s ecifications for
learner will be able to:  Credits	CLO101.3: Explain the behave systems with the heave systems with the heave close to the close of	them in various semiconductions various semiconductions vior of Metal oxide semiconduction of energy band diagrams.  T devices with desired spendications.  Practical	nductor (MOS) s ecifications for
Credits  Teaching Hours per week	switching and amp CLO101.3: Explain the behave systems with the head of the close o	them in various semiconductions various semiconductions vior of Metal oxide semiconduction oxide se	nductor (MOS) s ecifications for  Total 4 4 30
Credits  Teaching Hours per week Internal Assessment Marks	switching and amp CLO101.3: Explain the behave systems with the heave CLO101.4: Develop MOSFE electronic circuit a Theory 4 4 30	them in various semiconductions various semiconductions vior of Metal oxide semiconduction of Metal oxide semiconduction of Metal oxide semiconduction of Metal oxide semiconduction oxide semiconduct	nductor (MOS) secifications for Total 4 4 30 70
Teaching Hours per week	switching and amp CLO101.3: Explain the behave systems with the head of the close o	them in various semiconductions various semiconductions vior of Metal oxide semiconally of energy band diagrams.  T devices with desired spenapplications.  Practical  0  0 0	nductor (MOS) s ecifications for  Total 4 4 30

Instructions for Paper- Setter: The examiner will set 9 questions asking two questions from each unit and one compulsory question by taking course learning outcomes (CLOs) into consideration. The compulsory question (Question No. 1) will consist at least 4 parts covering entire syllabus. The examinee will be required to attempt 5 questions, selecting one question from each unit and the compulsory question. All questions will carry equal marks.

marks. Unit	Topics		CLOs	
1	Band model in solids, donors and acceptors. Mass-Action law, effective mass. Carrier concentrations, Fermi level, Equilibrium Conditions-Electrons and holes, temperature dependence of carrier concentrations, compensation and space charge neutrality. Conductivity and mobility. Drift velocity and resistance, scattering, effect of temperature and doping on mobility, high field effect-velocity limitations, Hall effect	15	CLO101.1	
	Equilibrium in Electronic System, Idealized Metal-semiconductor junction, Current-voltage characteristics, non-rectifying contacts, Surface effects			
II	The pn junction, potential barrier, contact potential, equilibrium fermi levels, space charge at junction, forward and reverse biased junctions; Depletion width, electric field at junction, capacitance of pn junctions, (all concepts with suitable band diagrams) Reverse bias breakdown. Zener breakdown, avalanche breakdown  Fundamentals of BJT operation, amplification with BJT's, BJT fabrication/structure (BJT for integrated circuits), terminal currents, Other important effects- drift in base region, base narrowing, avalanche breakdown, injection levels-thermal effects. Base resistance and emitter crowding, kirk effect,	15	CL:O101.2	

	Total Contact Hours	60	
IV	Basic MOSFET behaviour, Strong inversion region, current voltage characteristics, pinch off and saturation, Channel length modulation, body bias effect, Improved Models for short channel MOSFETs.  Designing of MOSFET based amplifier circuits in common source configuration. Type of MOSFET Scaling – constant voltage and constant field scaling, short channel effects in MOSFET devices, Gate coupling, velocity overshoot, high field effects, substrate current, Hot carrier effects, Gate current, Device degradation, Structure that reduce the drain field.	15	CLO101
Ш	Equilibrium in Electronic System, Idealized Metal-semiconductor junction, Current-voltage characteristics, non-rectifying contacts, Surface effects MOS structure, Ideal MOS capacitor, thermal equilibrium band diagrams, Polysilicon and metals as gate electrode materials, the flat band voltage, MOS Electronics -thermal equilibrium and nonequilibrium conditions, threshold voltage, Capacitance of MOS system- CV behaviour of Ideal MOS system, non-ideal MOS system- Effect of real surface, work function difference. Oxide and Interface charges, threshold voltage in presence of oxide charges	15	CLO101.3
	Designing of amplifier circuits with BJT devices in common emitter configuration with (using emitter resistance) and without negative feedback		

## Recommended Books/e-resources/LMS:

- Solid State Electronic Devices (6th edition) Ben G Streetman & S.K.Banerjee. (PHI, New Delhi, 2009)
- Device Electronics for Integrated Circuits (3rd Edition) Muller & Kammins- John Wiley
- Physics and Technology of Semiconductor Devices by A.S. Grove.
- Physics of Semiconductor Devices by S.M.Sze.

valuation M Outcomes				End Semester Examination (70 Marks)
	Mid Term Exam	Seminar/Presentation/ Assignment/Quiz/Test	Class Participation	SEE.
Marks:	15	10	5	70
CLO101.1	7.5	-		17
CLO101.2	7.5		-	17
CLO101.3	1.0	5		18
CLO101.3	1	5		18

	w.e.f. Session: 2024-25			
	Part A - Introduction			
Name of Programme	M.Sc. Electronic Science			
Semester	First			
Name of the Course	IC Fabrication Technology			
Course Code	M24-ELE-102		_	
Course Type	CC2			
Level of the course	400-499			
Pre-requisite for the course	NIL	_	fabrications	
After completing this course, the learner will be able to:	technique/tools a thin films. CLO102.2: Describe the kinc and controlling	nd instrumentation used for		
	semiconductors. CLO102.3: Differentiate bettechniques used thin films and bu CLO102.4: Explain the process	ween various semicondu for patterning (lithography lk structures. ess sequence for BJT, CMC	etor processing and etching) of	
	semiconductors. CLO102.3: Differentiate bet techniques used thin films and bu CLO102.4: Explain the processes and the	ween various semicondu for patterning (lithography lk structures. ess sequence for BJT, CMC	etor processing and etching) of	
Credits	semiconductors. CLO102.3: Differentiate bettechniques used thin films and bu CLO102.4: Explain the process	tween various semicondured for patterning (lithography lk structures. less sequence for BJT, CMC eir packaging.	etor processing and etching) of OS and BiCMOS	
	semiconductors. CLO102.3: Differentiate bettechniques used thin films and but CLO102.4: Explain the processes and the Theory	tween various semicondus for patterning (lithography lk structures. ess sequence for BJT, CMC eir packaging.  Practical  0 0	etor processing and etching) of DS and BiCMOS  Total	
Teaching Hours per week	semiconductors. CLO102.3: Differentiate bet techniques used thin films and bu CLO102.4: Explain the processes and the	tween various semicondu for patterning (lithography lk structures. ess sequence for BJT, CMC eir packaging.  Practical  0  0  0	etor processing and etching) of DS and BiCMOS  Total  4  4  30	
Teaching Hours per week Internal Assessment Marks	semiconductors. CLO102.3: Differentiate bettechniques used thin films and bu CLO102.4: Explain the processes and the Theory 4 4 30 70	tween various semicondu for patterning (lithography lk structures. ess sequence for BJT, CMC eir packaging.  Practical  0  0  0  0  0	etor processing and etching) of DS and BiCMOS  Total 4 4 30 70	
Teaching Hours per week	semiconductors. CLO102.3: Differentiate bettechniques used thin films and bu CLO102.4: Explain the proce Processes and the Theory 4 4 30	tween various semicondu for patterning (lithography lk structures. ess sequence for BJT, CMC eir packaging.  Practical  0  0  0	etor processing and etching) of DS and BiCMOS  Total  4  4  30	

Instructions for Paper- Setter: The examiner will set 9 questions asking two questions from each unit and one compulsory question by taking course learning outcomes (CLOs) into consideration. The compulsory question (Question No. 1) will consist at least 4 parts covering entire syllabus. The examinee will be required to attempt 5 questions, selecting one question from each unit and the compulsory question. All questions will carry equal marks.

marks. Unit	Topics	Contact Hours	CLOs
1	Microelectronics processing: Introduction, Clean Room, Pure Water System, Vacuum Science and Technology, Practical vacuum systems, Operating principle: Rotary Pump, Cryo Pump and Turbo Molecular Pump, Vacuum Gauges: Pirani and Penning Gauge, Sources for vacuum deposition, Sputtering (DC, RF and RF Magnetron), Chemical Vapor Deposition, reactors for chemical vapor deposition, CVD Applications, PECVD, Metallization, Epitaxy: Introduction, Vapor phase epitaxy, Liquid phase epitaxy and Molecular beam epitaxy. Hetroepitaxy.	15	CLO102.1
IJ	Thermal Oxidation of Silicon, Oxide Formation, Kinetics of Oxide Growth, Oxidation Systems, Properties of Thermal Oxides of Silicon, Impurity Redistribution during Oxidation, Uses of Silicon Oxide, Basic diffusion process, Diffusion Equation, Diffusion Profiles, Evaluation of Diffused Layers, Diffusion in Silicon, Emitter-Push Effect, Lateral Diffusion, Distribution and Range of Implanted Ions, Ion Distribution, Ion Stopping, Ion Channeling, Disorder and Annealing, Multiple Implantation and Masking, Pre-	15	CLO102.2

	deposition and Threshold Control.		
111	Photolithography. Negative and Positive Photoresist. Resist Application. Exposure and Development. Photolithographic Process Control. E-Beam Lithography. X-Ray Beam Lithography and Ion Beam Lithography. Wet Chemical Etching, Chemical Etchants for SiO <sub>2</sub> , Si <sub>3</sub> N <sub>4</sub> , Polycrystalline Silicon and other microelectronic materials, Plasma Etching, Plasma Etchants, Photoresist Removal Lift off process, Etch Process Control	15	CLO102.3
IV	PMOS. NMOS and CMOS IC technology-fabrication steps with mask layout, MOS Memory technology- Static and Dynamic, Bipolar IC Technology, BiCMOS Technology, Packaging design considerations, Special package considerations, Yield loss in VLSI, Reliability requirements for VLSI.	15	C1.O102.4
	VLSI, Reliability requirements for VLSI.  Total Contact Hours	60	

# Recommended Books/e-resources/LMS:

- 1. Microelectronic Processing: An Introduction to the Manufacture of Integrated Circuits by W. Scot Ruska (McGraw Hill International Edition).
- 2. VLSI Technology by S. M. Sze (2nd Edition)
- 3. Microchip Fabrication: A Practical Guide to Semiconductor Processing by Peter Van Zant (2nd Edition) (McGraw Hill Publishing Company).
- 4. Vacuum Technology by A. Roth
- 5. Semiconductor Devices: Physics and Technology by S.M. Sze.
- 6. VLSI Fabrication Principles: Silicon and Gallium Arsenide by Sorab K. Ghandhi (John Wiley & Sons).

### Evaluation Method

Outcomes	Internal Assessment (30 Marks)			End Semester Examination (70 Marks)
	Mid Term Exam	Seminar/Presentation/ Assignment/Quiz/Test	Class Participation	SEE
Marks:	15	10	5	70
CLO102.1	7.5		-	17
CLO102.2	7.5			
CLO102.3		5		18
CLO102.4		5		10

	w.e.f. Session: 2024	-25	
	Part A - Introduct	tion	
Name of Programme	M.Sc. Electronic Science		
Semester	First		
Name of the Course	EM Theory and Electronic	e Communication	
Course Code	M24-ELE-103		
Course Type	CC3		
Level of the course	400-499		
Pre-requisite for the course	NII.		
Course Learning Outcomes (CLC After completing this course, the learner will be able to:	CLO103.1: Explain wave CLO103.2: Understand the impedance material CLO103.3: Explain various CLO103.4: Understand the satellite communications of the communication of the commun	teching us pulse and digital modula ne basics of modern tele	ation techniques.
er P	Theory	Practical	Total
Credits	4	0	4
Teaching Hours per week	4	0	-
Internal Assessment Marks	30	0	30
End Term Exam Marks	70	0	70
Max. Marks	100	0	100
Examination Time	3 hours		

Instructions for Paper- Setter: The examiner will set 9 questions asking two questions from each unit and one compulsory question by taking course learning outcomes (CLOs) into consideration. The compulsory question (Question No. 1) will consist at least 4 parts covering entire syllabus. The examinee will be required to attempt 5 questions, selecting one question from each unit and the compulsory question. All questions will carry equal marks.

marks. Unit	Topics	Contact Hours	CLOs
ı	Wave Equation and Boundary conditions, Plane monochromatic wave in non-conducting media, conducting media, Reflection and refraction at the boundary of two non-conducting media-oblique incidence. Reflection from a conducting plane-total internal reflection. Propagation between parallel conducting plates, Radio Wave propagation: Propagation in Free space. Tropospheric Propagation. Ionospheric propagation. Surface wave propagation, Propagation losses	15	CLO103.1
IJ	Transmission lines. Characteristic impedance, standing waves, quarter and many wavelength lines. Impedance matching. Use of Smith Chart, Impedance matching using Smith Chart, Losses in Transmission lines, Wave-guides: Rectangular, losses in Wave-guides. S Parameters, Basics of Antennas: Antenna parameters, Dipole antennas, Radiation pattern, Antenna	15	CLO103.2
111	Pulse Communication, Pulse Amplitude modulation (PAM). Pulse Width Modulation, Pulse Position Modulation (PPM), Pulse Code Modulation and application.  Digital Communication, Characteristics of Data Transmission Circuit, Data Transmission speeds, Noise, Cross talks, Echo suppressors, Distortion, Equalizers, Bit transmission, Signaling rate, Digital Communication techniques, LEGE BESK OPSK DPSK, Error Detection and Correction codes.	15	CLO103.3
	Modern Telephone networks, mobile telephone network, intelligent network and		

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Satellite Communication: Introduction, Orbits, Station keeping, Satellite Attitude, Transmission Path, Path Loss, Noise considerations, the Satellite Systems, Saturation flux density, Effective Isotropic radiated Power, Multiple	15	CLO103.4
Access Methods.  Total Contact Hours	60	

# Recommended Books/e-resources/LMS:

- 1. Foundations of Electromagnetic Theory JR Reitz and FZ by Reitz and Milford (Addison Wesley).
- 2. Electromagnetics by B.B. Laud (Wiley Eastern).
- 3. Mathew N. O. Sadiku, 'Principles of Electromagnetics', 6th Edition, Oxford University Press Inc. Asian edition, 2015.
- 4. Theory and Applications of Microwaves by Brownwell and Beam (McGraw Hill).
- 5. Electronic Communication by George Kennedy.
- 6. Basic Electronic Communication by Roody & Coolen.
- 7. Electronic Communications System by Wayne Tomasi (Pearson).

Evaluation	Meth	od
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Valuation Mo Outcomes	Ciliou	Internal Assessment (30 Marks)		End Semester Examination (70 Marks)
	Mid Term Exam	Seminar/Presentation/ Assignment/Quiz/Test	Class Participation	SEE
N 4 1	15	10	5	70
Marks:	13			17
CLO103.1	7.5	-		17
CLO103.2	7.5			17
	10.7.91	5		18
CLO103.3				18
CLO103.4		3		1.00

	w.e.f. Session: 2024	-25	
	Part A - Introduct	tion	
Name of Programme	M.Sc. Electronic Science		
Semester	First		
Name of the Course	Electronic Instrumentation and Control System		
Course Code	M24-ELE-104		
Course Type	CC4		
Level of the course	400-499		
Pre-requisite for the course Course Learning Outcomes (CLC	NII.		
After completing this course, the learner will be able to:	CLO104.2: Understand di quantity and remeasuring the CLO104.3: Identify different design these for the close of the close	fferent methods for measi- ole of different instrument same rent control systems, analy- for specified purpose	uring a physical tation required for vze using SFG and bility analysis of the
Credits	Theory	Practical	Total
Credits	4	0	4
Teaching Hours per week	4	0	4
Internal Assessment Marks	30	0	30 70
End Term Exam Marks	70	0	100
Max. Marks	100	0	100
Examination Time	3 hours		

Instructions for Paper- Setter: The examiner will set 9 questions asking two questions from each unit and one compulsory question by taking course learning outcomes (CLOs) into consideration. The compulsory question (Question No. 1) will consist at least 4 parts covering entire syllabus. The examinee will be required to attempt 5 questions, selecting one question from each unit and the compulsory question. All questions will carry equal marks.

marks. Unit	Topics	Contact Hours	CLOs
1	Basic concepts of measurement: Introduction, system configuration basic characteristics of measuring devices, Transducer Classification :Introduction, Electrical transducer, classification, basic requirements. Performance characteristics of an instrumentation system: generalized system, zero order, first order, second order system, Measurement of displacement: principle of transduction. Variable resistance device, LVDT, Variable capacitance transducer. Hall effect devices, Measurement of pressure: Thin film pressure transducer, piezoelectric pressure transducer vibrating element pressure transducer.	15	CLO104.1 CLO104.2
П	Measurement of position, velocity, force, torque (basics only). Measurement of flow: Head type flow meters based on differential pressure measurements. Anemometers, Temperature measurements: resistance type temp. sensors, thermistors, thermocouples, solid state sensors, optical pyrometers, Measurement of humidity, thickness, pH (basics only). Instrumentation applifier, O meter, Digital storage oscilloscope, Lock-in Amplifier.	15	C1.O104.2
	Bioelectrical signals and their measurement. Electrodes for ECG Control System: Introduction: Basic components of a control system. Example		

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111	of control system applications, Open loop and closed loop control system, Feedback and its effects, Types of feedback control systems, Transfer functions, block diagram, and Signal Flow graphs. Time response of feedback control systems: Steady state error analysis, Introduction and design of P, 1 PI, PD and PID Controllers.	15	CLO104.3 CLO104.4
IV	Stability of linear control systems: introduction, Methods of determining stability, Routh –Hurwitz stability, Nyquist Stability Criterion, Root loci technique for analysis of LTI control system, Bode plots and Nyquist plots.  Introduction to State variable analysis: Concepts of state, state variable and state models for electrical systems, Solution of state equations.	15	CLO104.3 CLO104.4
	Total Contact Hours		60

### Recommended Books/e-resources/LMS:

- 1. Modern Electronic Instrumentation and Measurement Technique by Alfred D. Helfrick and William D. Cooper, (Eastern Economy Edition)
- 2. Instrumentation Devices and Systems by C.S. Rangan, G.R. Sarma and V.S.V Mani, Tata McGraw Hill.
- 3. Principles of Measurement and Instrumentation by Alan S. Morris, Prentice Hall.
- 4. Automatic Control Systems by Benjamin C. Kuo, Prentice Hall India.
- 5. Modern Control Engineering by K. Ogata, PHI.
- 6. Bio-Medical Instrumentation by R.S Khandpur.

valuation M Outcomes	Cinod	Internal Assessmen (30 Marks)	t	End Semester Examination (70 Marks)
	Mid Term Exam	Seminar/Presentation/ Assignment/Quiz/Test	Class Participation	SEE
Marks:	15	10	5	70
CLO104.1	7.5			17
CLO104.2	7.5			17
CLO104.3		5		18
CLO104.4		5		18



	w.e.f. Session	n: 2024	1-25		
	Part A - Int	troduc	tion		
Name of the Programme	M.Sc Electronic Sc	eience			
Semester	First	8			
Name of the Course	Analog Circuits De	esign L	ab		
Course Code	M24-ELE-105				
Course Type	PC1				
	400-499				
Level of the course					
Pre-requisite for the course Course Learning Outcomes (CLC	NIL				
After completing this course, the learner will be able to:  Credits	CLO105.3: Analyse CLO105.4: Present t	(Diode ent app & inte the exp	/BJT/MOSFET). lication-oriented circuit rpret the data obtained erimental results and cort in clear and concise near the concise of the conci	ts using Op- in the exper	amp &555
	0		4		
Teaching Hours per week	0		8		8
Internal Assessment Marks	0		30		30
End Term Exam Marks	0		70		70
Max. Marks	0		100		100
Examination Time	0			nours	
	Part B- Contents	of the	Course		
	Practicals				Contact Hours
(List of experiments given here avery semester, as per the availability Tar.)  1. Familiarization with electronic 2. Bipolar Junction Transistor bas 3. Plot MOSFET characteristics at 4. Design of analog Multimeter 5. IC 555 applications: Monoshot, 6. OP- AMP based applications: Sample of the company of th	entative list of experiise and equiventative list of experiis instruments like CRO, ed Amplifier Design (was design common sour Astable, Bistable mult ample and hold circuits or, Triangular, Square & Order) – Low Pass, High extern and metal film design entations.	ipment) ments Multin vith & v ree amp ivibrate s, logar s sine v n Pass, eposition	neter, Function Generat without Feedback) plifier. or, Schmitt Trigger etc, ithmic amplifier precisi vaver generators Band Pass, Band Rejecton using thermal evapor	or etc.	120
Internal Assessn	ient: 30		End Term Exa	amination:	70
> Practicum		30	> Practicum	70	uice\$25
Class Participation:		5	Lab record, Viva-V	oce, write-	up and
Seminar/Demonstration/Viva-voc	e/Lab records etc.:	10	execution of	the practica	
Mid-Term Exam:		15			
	Part C-Learning	Resou	rces		
Lab Manual of respective exp					

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2	w.e.f. Session			
N. Cal B	Part A - In	troduc	ction	
Name of the Programme	M.Sc Electronic Sci	ence		
Semester	First			
Name of the Course	Digital Circuit Design	gn & P	rogramming Lab	
Course Code	M24-ELE-106			
Course Type	PC2			
Level of the course	400-499			
Pre-requisite for the course (if any)	NIL			
Course Learning Outcomes (CLO)	devices/10	_S		l circuits using CMOS
After completing this course, the learner will be able to:	Solving so	cientifi	c problems	l computer language fo
	CLO106.3: Analyse &	inter	pret the data obtained i	n the experiments
	CLO106.4: Present th	e expe	rimental results and co	nclusions in the form o
Credits		port in	clear and concise man	
Credits	Theory		Practical	Total
Toophing House	0		4	4
Teaching Hours per week Internal Assessment Marks	0		8	8
End Term Exam Marks	0		30	30
Max. Marks	0		70	70
Examination Time	0		100	hours 100
	Part B- Contents	of the		nours
	Practicals			Contact Hours
(List of experiments given he beginning of every semeste	ere is tentative. It will be r as per the availability	of expe	wed and updated at the ertise and equipment)	
<ol> <li>Familiarization with Study of</li> <li>Design of digital inverter circuments from the transfer curve.</li> <li>Design of synchronous and as</li> <li>Implementation of half adder</li> <li>A/D and D/A converter circuments.</li> <li>C-Programming- logical, arith</li> <li>C-Programming- numerical ments.</li> <li>Plot device characteristics usin</li> <li>Programming using MATLA</li> </ol>	uits using BJT devices a ynchronous digital coun and full adder circuit us ts. imetic, decision making ns, functions & subrouti ethods	nd find iters. ing CM	10S digital ICS.	
	Evaluation M	1ethod		
Internal Assessi	ment: 30		End Term Ex	amination: 70
Practicum		30	> Practicum	70
Class Participation:		5	Lab record, Viva-	Voce, write-up and
Seminar/Demonstration/Viva-voc	e/Lab records etc.:	10	execution of	the practical
Mid-Term Exam:		15		
	Part C-Learning	Resou	rces	
ecommended Books/e-resources/	LMS:			
<ul> <li>Lab manuals of respective</li> </ul>	experiments			

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	w.e.f. Session: 2024-25
Name of the Programme	M.Sc Electronic Science
Semester	First
Name of the Course	Seminar
Course Code	M24-ELE-107
Course Type: (CC/DEC/PC/Seminar/CHM/O EC/EEC)	Seminar
Level of the course	400-499
Course Learning Outcomes (CLO) After completing this course, the earner will be able to:	CLO107.1: Establish motivation for any topic of interest in the field of electronics and analyze and data from literature survey.  CLO107.2: Effective presentation and improve soft skills using new and recent technology for creating technical reports/presentation
Credits	Seminar
	2
Teaching Hours per week	2
Max. Marks	50
Internal Assessment Marks	0
End Term Exam Marks	50
Examination Time	l hour

<u>Instructions for Examiner:</u> Evaluation of the seminar will be done by the internal examiner(s) on the parameters as decided by staff council of the department. There will be no external examination/viva-voce examination.



	w.e.f. Session: 2024-	-25	
	Part A - Introduct	ion	
Name of Programme	M.Sc. Electronic Science		
Semester	Second		
Name of the Course	Digital Circuits and System	m Design	
Course Code	M24-ELE-201		
Course Type	CC5		
Level of the course	400-499		
27 E. 045 - 04 - 0 0-1-7779529484	NIL		o v - v - v - v
			S logic families applementation of
After completing this course, the learner will be able to:	basic circuits i CLO201.3: Analyze and d CLO201.4: Define Impedi	esign of State Machines	sign Methodology
Credits	Theory	Practical	Total
Credits	4	0	-1
Teaching Hours per week	.1	()	1
Internal Assessment Marks	30	0	30
End Term Exam Marks	70	0	70
Max. Marks	100	0	100
Examination Time	3 hours		

Instructions for Paper- Setter: The examiner will set 9 questions asking two questions from each unit and one compulsory question by taking course learning outcomes (CLOs) into consideration. The compulsory question (Question No. 1) will consist at least 4 parts covering entire syllabus. The examinee will be required to attempt 5 questions, selecting one question from each unit and the compulsory question. All questions will carry equal marks.

marks. Unit	Topics	Contact Hours	(1.Os
1	Introduction to CMOS Circuits, Logic families. CMOS logic, Electrical behaviour of CMOS circuits, CMOS steady state electrical behaviour, CMOS dynamic electrical behaviour, CMOS Input and Output structures, CMOS logic families. CMOS/TTL interfacing, Timing Hazards, Quine-McCluskey Method of finding Minimal SOP and POS Expressions.	14	CLO201.1
11.	Combinational Logic Design Practice: Documentation standards, Circuit timing. Combinational PLDs: Programmable logic array (PLA). Implementation of combinational logic using PLA, Programmable array logic (PAL), Generic Array logic (GAL), Description of some basic PLDs, Complex Programmable Logic Devices (CPLDs), Combinational PLD applications.  Implementation of following in VHDL decoders, encoders, three state devices multiplexers, exclusive-OR gates and parity circuits, comparators, adders	16	CLO201.2
111	Bistable elements, Latches and Flip-Flops, Clocked Synchronous State-machine Analysis. Clocked Synchronous State-machine Design. Designing State Machine Synthesis using Transition Lists.	15	CLO201.3
IV	Sequential PLDs, Registers: Shift Registers and counters, Iterative versus Sequential Circuits, Synchronous Design Methodology, Impediments to Synchronous Design, Synchronizer Failure and Meta stability. Field Programmable Gate Arrays.	15	CLO201.4
	Programmable Gate Arrays.  Total Contact		60

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Hours

# Part C-Learning Resources

# Recommended Books/e-resources/LMS:

1. Digital Design: Principles & Practices-John F. Wakerly (4th edition, Prentice Hall).

2. Programmable Logic: PLDs and FPGAs- R.C. Seals, G.F. Whapshott (McGraw-Hill, Publication)

**Evaluation Method** 

Outcomes		Internal Assessment (30 Marks)		End Semester Examination (70 Marks)
	Mid Term Exam	Seminar/Presentation/ Assignment/Quiz/Test	Class Participation	SEE.
Marks:	15	10	5	Transport 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1
CLO201.1	7.5	-	2	70
CLO201.2	7.5		-	17
CLO201.3	7.10	-	-	
CLO201.4		3		18
1.0201.4		5		1.8

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	w.e.f. Session: 2	024-25	
	Part A - Introd	uction	
Name of Programme	M.Sc. Electronic Scien	ce	
Semester	Second		
Name of the Course	Analog CMOS Integral	ted Circuits	
Course Code	M24-E1.E-202		
Course Type	CC6		
Level of the course	400-499		
Pre-requisite for the course	M24-ELE-101		
A G	C1 0202 2	circuit simulation.	
After completing this course, the carner will be able to:	CLO202.3: Analyze the systems in in CLO202.4: Differentiate	us analog building blocks netive resistors using MOS performance of MOSF tegrated circuits. between various configure	FET devices. ET based amplifier
carner will be able to:	CLO202.3: Analyze the systems in in CLO202.4: Differentiate	us analog building blocks letive resistors using MOS performance of MOSF tegrated circuits.  between various configurormance of Integrated Circuits	FET devices. FET based amplifier rations of op-amp in uits.
carner will be able to:	CLO202.3: Analyze the systems in in CLO202.4: Differentiate terms of performs	us analog building blocks active resistors using MOS performance of MOSF tegrated circuits.  between various configurormance of Integrated Circuits.  Practical	FET devices. ET based amplifier
Credits  Ceaching Hours per week	CLO202.3: Analyze the systems in in CLO202.4: Differentiate terms of perfo	us analog building blocks letive resistors using MOS performance of MOSF tegrated circuits. between various configur ormance of Integrated Circ Practical 0	FET devices. FET based amplifier rations of op-amp in uits.
Credits  Ceaching Hours per week Internal Assessment Marks	CLO202.3: Analyze the systems in in CLO202.4: Differentiate terms of performance the control of	us analog building blocks netive resistors using MOS performance of MOSF tegrated circuits. between various configurormance of Integrated Circ Practical  0 0	FET devices. FET based amplifiers rations of op-amp in uits.  Total  4
Credits  Ceaching Hours per week Internal Assessment Marks and Term Exam Marks	CLO202.3: Analyze the systems in in CLO202.4: Differentiate terms of performance of the control	us analog building blocks active resistors using MOS performance of MOSF tegrated circuits. between various configur ormance of Integrated Circ Practical 0 0 0	FET devices. FET based amplifiers rations of op-amp in uits.  Total 4 4 30
Credits  Ceaching Hours per week Internal Assessment Marks	CLO202.3: Analyze the systems in in CLO202.4: Differentiate terms of performance of the control	us analog building blocks netive resistors using MOS performance of MOSF tegrated circuits. between various configurormance of Integrated Circ Practical  0 0	FET devices. FET based amplifiers rations of op-amp in uits.  Total  4

Instructions for Paper- Setter: The examiner will set 9 questions asking two questions from each unit and one compulsory question by taking course learning outcomes (CLOs) into consideration. The compulsory question (Question No. 1) will consist at least 4 parts covering entire syllabus. The examinee will be required to attempt 5 questions, selecting one question from each unit and the compulsory question. All questions will carry equal marks.

Unit	Topics	Contact Hours	CLOs
1	Device Modeling, DC models, small signal models, use of device models in circuit analysis, diode models, de diode model, small signal diode model. HF diode model, MOS models, large signal (or de) MOSFET model, small signal MOSFET model, HF MOSFET model, short channel Devices, sub-threshold MOS Models, Modeling noise sources in MOSFET's.  MOS Device Layouts, Circuit simulation, Circuit simulation using SPICE, MOS—SPICE Models,	1-4	CLO202.1
IJ	MOS switches, MOS Diode/active resistors, Current sources and sinks, Basic Current Mirrors, Cascoded Current Mirror, Widlar & Wilson Current mirror CMOS amplifiers: Single stage MOS Inverting Amplifier with various load configurations (resistive, diode connected, and current source as load), CMOS Push Pull amplifier	15	CLO202.2
Ш	Differential amplifiers: Qualitative and quantitative analysis. CMOS differential amplifiers -Differential pair with active loads, Differential pair with current source and current mirror load,  Frequency response of Amplifiers: Concept of zeros and poles, Miller effect, Association of poles with nodes, frequency response of MOS inverting amplifiers and differential amplifiers.	16	C1.O202.3

stage op-amp Simulation a	ept of phase margin, frequency compensation, compensation of two and measurement of op-amps, Comparators, characterization of High gain comparators, Propagation delay of two-stage	15	CLO202,4
10 1		1:3	(1.0/202,4

### Recommended Books/e-resources/LMS:

- L. Design of analog CMOS Integrated Circuits, Behzad Razavi, Tata McGraw Hill
- 2. VLSI Design Techniques for Analogue and Digital Circuits by R.L. Geiger, P.E. Allen and N.R. Strader.
- 3. Analysis and Design of Analogue I.C's (2nd edition) by P.R. Gray, R.G. Meyer.
- 4. The SPICE book by Andrei Vladimirescu.
- 5. Computer Simulation of Electronic Circuits by Raghuram.

**Evaluation Method** 

Outcomes		Internal Assessme (30 Marks)	End Semester Examination (70 Marks)	
	Mid Term Exam	Class I in the patto		SEE
Marks:	15	10	5	70
CLO202.1	7.5	-	-	17
CLO202.2	7.5		-	17
CLO202.3		5		18
CLO202.4		5		18

	w.e.f. Session: 20	24-25			
	Part A - Introdu	iction			
Name of Programme	M.Sc. Electronic Science	e			
Semester	Second				
Name of the Course	Verilog Hardware Descri	ription Language	*		
Course Code	M24-ELE-203	16 389			
Course Type	CC7		-		
Level of the course	400-499				
Pre-requisite for the course	NIL				
Course Learning Outcomes (CLC After completing this course, the learner will be able to:	Language CLO203.2: Design Veril Dataflow and CLO203.3: Design Veril	og models for digital ci Switch level modelling og models for digital ci ng, and using Generate bl IDPs and the concept of s	reuits using Gate lever reuits using behavioura		
Credits	Theory	Practical	Total		
	4	0	4		
Teaching Hours per week	4	0	4		
Internal Assessment Marks	30	0	30		
End Term Exam Marks	70	0	70		
Max. Marks	100	0	100		
Examination Time	3 hours				

Instructions for Paper- Setter: The examiner will set 9 questions asking two questions from each unit and one compulsory question by taking course learning outcomes (CLOs) into consideration. The compulsory question (Question No. 1) will consist at least 4 parts covering entire syllabus. The examinee will be required to attempt 5 questions, selecting one question from each unit and the compulsory question. All questions will carry equal marks.

Unit	Topico	Contact Hours	CLOs
1	Benefits of CAD, Integrated circuit design techniques, Hierarchical design, Design abstraction, Computer aided design, Concepts of CPLD, FPGA. Introduction to HDLs, Verilog and its capabilities, Hierarchical Modeling Concepts: Design Methodologies, Modules, Instances, Components of Simulation and Test Bench, Basic Concepts: Lexical Conventions, Data Types, System Tasks and Compiler Directives, Modules and Ports.	15	CLO203.1
11	Gate-Level Modeling: Gate Types, Gate Delays. Dataflow Modeling. Continuous Assignments, Delays, Expressions, Operators, and Operands. Operator Types, Switch-Level Modeling: Switch-Modeling Elements.	15	CLO203.2
Ш	Behavioral Modeling: Structured Procedures, Procedural Assignments, Timing Controls, Conditional Statements, Multiway Branching, Loops, Sequential and Parallel Blocks, Generate Blocks, Tasks and Functions.	15	CLO203.3
IV	Timing and Delays, Types of Delay Models, Path Delay Modeling, Timing Checks, Delay Back-Annotation, User-Defined Primitives (brief), Programming Language Interface (brief), Logic Synthesis with Verilog, Synthesis Design Flow, Verification of Gate-Level Netlist, Verification Techniques (brief):	15	CLO203.4

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Traditional Verification Flow, Assertion Checking, Formal Verification	
Total Contact Hours	60
Part C-Learning Resources	

## Recommended Books/e-resources/LMS:

- 1. Custom VLSI Microelectronics by Stanley L.Hurst (Prentice Hall 1992)
- 2. Verilog HDL Samir Palnitkar (Pearson)
- 3. A Verilog HDl Primer J. Bhaskar (Pearson)
- 4. Modern VLSI Design- A Systems Approach- Wayne Wolf-PTR Prentice Hall-1994

#### **Evaluation Method**

Outcomes		Internal Assessment (30 Marks)		End Semester Examination (70 Marks)
	Mid Term Exam	Seminar/Presentation/ Assignment/Quiz/Test	Class Participation	SEE
Marks:	15	10	5	70
CLO203.1	7.5		-	17
CLO203.2	7.5		-	17
CLO203.3		5		18
CLO203.4		5		18

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	w.e.f. Session: 202	4-25			
	Part A - Introduc	etion			
Name of Programme	M.Sc. Electronic Science				
Semester	Second				
Name of the Course	Introduction to Embedded S	ystems			
Course Code	M24-ELE-204		-		
Course Type	CC8				
Level of the course	400-499				
Pre-requisite for the course	NIL				
Course Learning Outcomes (CLO)	CLO204.1: Understand need and applications of the Embedded Systems CLO204.2: Analyse given problem and write programs using 8051 assembly language				
After completing this course, the learner will be able to:	CLO204.3: Design interfacin CLO204.4: Understand the is				
Credits	Theory	Practical	Total		
	4	0	4		
Teaching Hours per week	4	0	+		
Internal Assessment Marks	30	0	30		
End Term Exam Marks	70	0	70		
Max. Marks	100	0	100		
Examination Time	3 hours				

<u>Instructions for Paper- Setter:</u> The examiner will set 9 questions asking two questions from each unit and one compulsory question by taking course learning outcomes (CLOs) into consideration. The compulsory question (Question No. 1) will consist at least 4 parts covering entire syllabus. The examinee will be required to attempt 5 questions, selecting one question from each unit and the compulsory question. All questions will carry equal marks.

Unit	Topics	Contact Hours	CLOs
1	Introduction to Embedded Systems: what is an Embedded system? . Embedded Systems vs General Computing Systems, Classification, major application areas, purpose of Embedded Systems, Wearable devices as an example of Embedded Systems  The Typical Embedded system: Core of Embedded System, Memory, Sensors and Actuators, Communication Interface, Embedded Firmware, other system components	15	C1.O204.1
П	Characteristics and Quality Attributes of Embedded Systems, Washing machine as application specific Embedded System and Automotive as domain specific embedded system  Designing Embedded Systems with 8bit Microcontrollers-8051: controller selection, why 8051?  Designing with 8051 Microcontroller: 8051 architecture, Memory Organization, Oscillator Unit, Ports, Interrupts, Timer Units, Serial Port, Reset Circuitry, Power saving modes	15	CLO204.2
111	Programming the 8051 Microcontroller: Addressing modes. Instruction Set – Data transfer, Arithmetic, Logical Instructions, Boolean Instructions, Program Control Transfer Instructions, ALP for implementation of Instruction set :binary to unpacked BCD, data transfer to internal and external memory, delay using timers  Design Examples: number display on LED. 7 segment display stopper motors	16	CLO204.3
	<b>Design Examples</b> : number display on LED, 7-segment display, stepper motor control, Analog to Digital Converter Interfacing, serial data transmission.		
	Hardware-Software Co-Design and Program Modelling: Issues in Hardware-		

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	Total Contact Hours		60
IV	Software Co-Design, Computational Models in Embedded Systems, Introduction to Unified Modelling Language.	14	C1.O204.4

### Recommended Books/e-resources/LMS:

- 1. Introduction to Embedded Systems: Shibu K. V. (TMH)
- Embedded Systems: Architecture, Programming and Design ,2<sup>nd</sup> Edition, Raj Kamal, Tata-McGraw Hill, 2011.
- 3. The 8051 Microcontroller and Embedded Systems Using Assembly and C Second Edition, Muhammad Ali Mazidi, Janice Gillispie Mazidi, Rolin D. McKinlay, Pearson.
- 4. Advanced Microprocessors and Peripherals, 3rd Edition, Ray and Bhurchandi, Tata McGraw Hill, 2006.
- 5. The 8051 Micro controller 3rd Edition, Keneth Ayala, Cengage Publishers.

#### **Evaluation Method**

Outcomes		Internal Assessment (30 Marks)	End Semester Examinatio (70 Marks)	
			Class Participation	SEE
Marks:	15	10	5	70
CLO204.1	7.5	-	-	17
CLO204.2	7.5			17
CLO204.3		5		18
CLO204.4		5		18

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	w.e.f. Session	: 2024	-25		
	Part A - Int	roduct	tion		
Name of the Programme	M.Sc Electronic Scie	nce			
Semester	Second				
Name of the Course	Electronic Circuit Simulation and Embedded Systems Lab				
Course Code	M24-ELE-205				
Course Type	PC3				
Level of the course	400-499				
	NIL NIL				
Pre-requisite for the course					
Course Learning Outcomes (CLO) After completing this course, the learner will be able to:	CLO205.2: Be proficie microcontrol CLO205.3: Analyze & CLO205.4: Present the	FET D ent in u roller-t interp exper	Devices using LTSPICE use of IDE's for designitions based system oret the data obtained in	and Cadence Tools ing, testing of the experiments clusions in the for	
Credits	Theory	Сроп	Practical Practical	Total	
	0		4	4	
Teaching Hours per week	0		8	8	
Internal Assessment Marks	0		30	30	
End Term Exam Marks	0		70	70	
Max. Marks	0		100	100	
Examination Time	0		4 }	nours	
	Part B- Contents	of the	Course		
	Practicals			Contact Hours	
(List of experiments given here beginning of every semester a <b>Tenta</b> 1. CMOS inverting Amplifier C  2. CMOS Differential Amplifie  3. Design and simulation of MC  4. Design and Simulation of Cu  5. Design and Simulation of firs  6. TCAD Simulation of semicor  7. Simulation of MEMS structu  8. Programming of 8051 using of Programming of 8051 using of Programming of 8051 using of Structus of External memories using the semicondary of the semicond	s per the availability of entive list of experiments. Circuits simulation using the sum of the sum	EDA ng ED scoded re Filte resses.	se and equipment)  Fools (Cadence Tools)  A Tools  d/Widler/Wilson)  er Circuits.	120	
Internal Assess		Tethou	End Term Ex	amination: 70	
> Practicum		30	> Practicum	70	
Class Participation:		5	Lab record, Viva-V		
Seminar/Demonstration/Viva-vo	ce/Lab records etc :	10	execution of		
	11.240 100/40 010//				
Mid-Term Exam:		15			
• Mid-Term Exam:	Part C-Learning		rces		



	w.e.f. Session: 2024			
	Part A - Introduc	tion		
Name of the Programme	M.Sc Electronic Science			
Semester	Second		20 T W	
Name of the Course	IC fabrication and characte	erizatio	n Lab	
Course Code	M24-ELE-206			
Course Type	PC4			
Level of the course	400-499			
Pre-requisite for the course (if any)	M24-ELE102		Cdustor	materials and device
Course Learning Outcomes (CLO) After completing this course, the learner will be able to:	CLO206.1: Measure the parameters of semiconductor materials and device CLO206.2: To use the techniques and equipment used for fabrication of semiconductor devices and integrated circuits.  CLO206.3: To Analyze and interpret experimental data  CLO206.4: Present the experimental results and conclusions in the of written report in clear and concise manner			
Credits	Theory		Practical	4
	0		4	8
Teaching Hours per week	0		8	30
Internal Assessment Marks	0		30	70
End Term Exam Marks	0		70	100
Max. Marks	0	-	100	ours
Examination Time	0	C.		ours
D.K.	Part B- Contents of	the Co	ourse	Contact Hours
	Practicals			Contact Hours
		40.00		
1. Study of Hall Effect 2. Resistivity measuremer 3. Study of PN junction pour study of optoelectronic Characteristics of semion of Study of Oxidation of Silicon was	ntative list of experiments  Intusing four probe setup arameters I devices and solar cell conductor power devices: I fers (both wet & Dry) and hotolithography (using pose and Aluminum film Contact Fabrication & char CV Characterization	JJT an oxide sitive p acteriz	nd SCR thickness photoresist)	120
Ter  1. Study of Hall Effect 2. Resistivity measuremer 3. Study of PN junction position of the study of proelectronic of the study of optoelectronic of the study of the stu	ntative list of experiments  Intusing four probe setup arameters devices and solar cell conductor power devices: I fers (both wet & Dry) and hotolithography (using pose and Aluminum film Contact Fabrication & char CV Characterization	JJT an oxide sitive p acteriz	nd SCR thickness photoresist) cation	120 samination: 70
Ter  1. Study of Hall Effect 2. Resistivity measurement 3. Study of PN junction position of the study of optoelectronic of the study of the s	ntative list of experiments  Intusing four probe setup arameters I devices and solar cell conductor power devices: I fers (both wet & Dry) and hotolithography (using pose and Aluminum film Contact Fabrication & char CV Characterization	JJT an oxide sitive p acteriz	nd SCR thickness photoresist) cation	
Ter  1. Study of Hall Effect 2. Resistivity measuremer 3. Study of PN junction position of the Study of optoelectronic op	ntative list of experiments  Intusing four probe setup arameters devices and solar cell conductor power devices: I fers (both wet & Dry) and hotolithography (using pose and Aluminum film Contact Fabrication & char CV Characterization	JJT an oxide sitive p acteriz	end SCR thickness shotoresist) tation  End Term Ex Practicum Lab record, Viva-	camination: 70 70 Voce, write-up and
Ter  1. Study of Hall Effect 2. Resistivity measuremer 3. Study of PN junction position of the study of optoelectronic o	ntative list of experiments  at using four probe setup arameters devices and solar cell conductor power devices: I afters (both wet & Dry) and hotolithography (using pose and Aluminum film Contact Fabrication & char CV Characterization  Evaluation Messessment: 30	JJT an oxide sitive pacterizethod	end SCR thickness shotoresist) tation  End Term Ex Practicum Lab record, Viva-	camination: 70
Ter  1. Study of Hall Effect 2. Resistivity measuremer 3. Study of PN junction position of Study of optoelectronic Study of optoelectronic Oxidation of silicon was measurement 7. Pattern transfer using position with the study of oxide at the study of oxide at the study of Study of Oxide at the study of Oxid	ntative list of experiments  at using four probe setup arameters devices and solar cell conductor power devices: I afters (both wet & Dry) and hotolithography (using pose and Aluminum film Contact Fabrication & char CV Characterization  Evaluation Messessment: 30	JJT an oxide sitive pacterizethod	end SCR thickness shotoresist) tation  End Term Ex Practicum Lab record, Viva-	camination: 70 70 Voce, write-up and
Ter  1. Study of Hall Effect 2. Resistivity measuremer 3. Study of PN junction position of the Study of optoelectronic of the Study of Oxidation of silicon was measurement of the Study of the Stud	ntative list of experiments  at using four probe setup arameters devices and solar cell conductor power devices: I afters (both wet & Dry) and hotolithography (using pose and Aluminum film Contact Fabrication & char CV Characterization  Evaluation Messessment: 30	JJT an oxide sitive pacterizethod  5 10 15	end SCR thickness shotoresist) tation  End Term Ex Practicum Lab record, Viva- execution of	camination: 70 70 Voce, write-up and

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